

# Extending Moore's Law with Nanotechnology

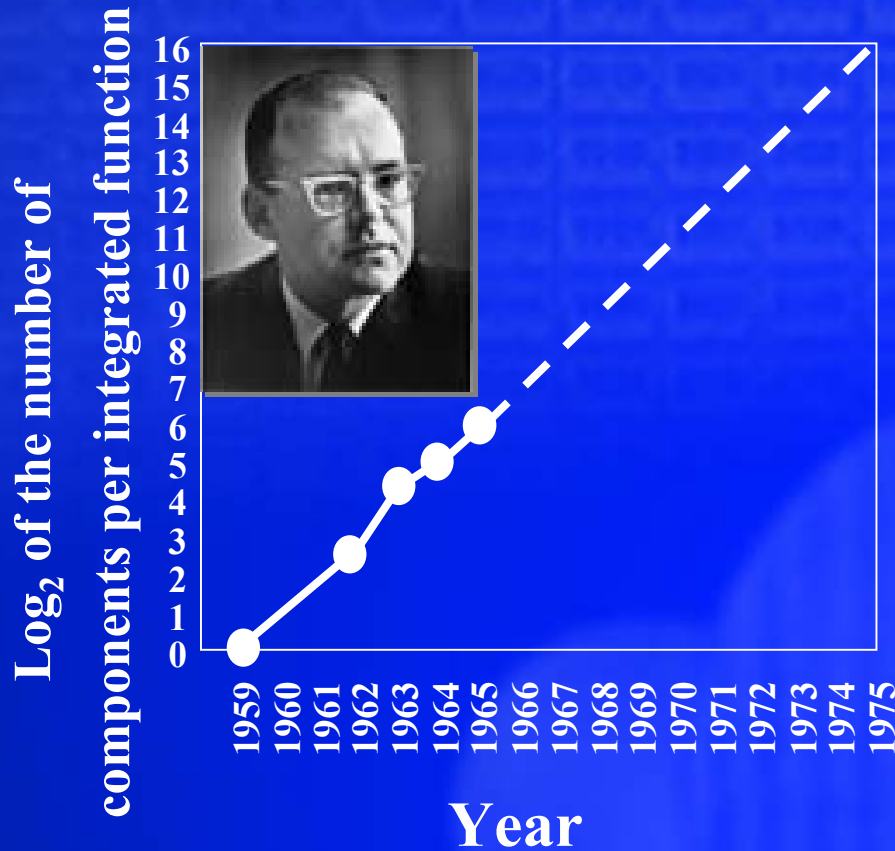
September 2003  
Carolyn Block, PhD  
Senior Staff Engineer  
Components Research  
Intel Corporation



# Agenda

- **Historical motivations for scaling**
- **Si Research at Intel**
  - Logic Technology Development
  - 90 nm Technology Results
- **Extending technology using Moore's Law**
  - Technical Criteria / Key Challenges
  - Research Directions: high K, trigate, nanotubes....
- **What comes next?**
- **Summary**

# Birth of Microelectronics: Moore's Law



“Reduced cost is one Of the big attractions of Integrated electronics, and The cost advantage continues To increase as the technology Evolves toward the production Of larger and larger circuit Functions on a single semiconductor substrate.”

“Dr. Gordon E. Moore is one of the new breed of electronic engineers, schooled in the physical sciences rather than in electronics.”



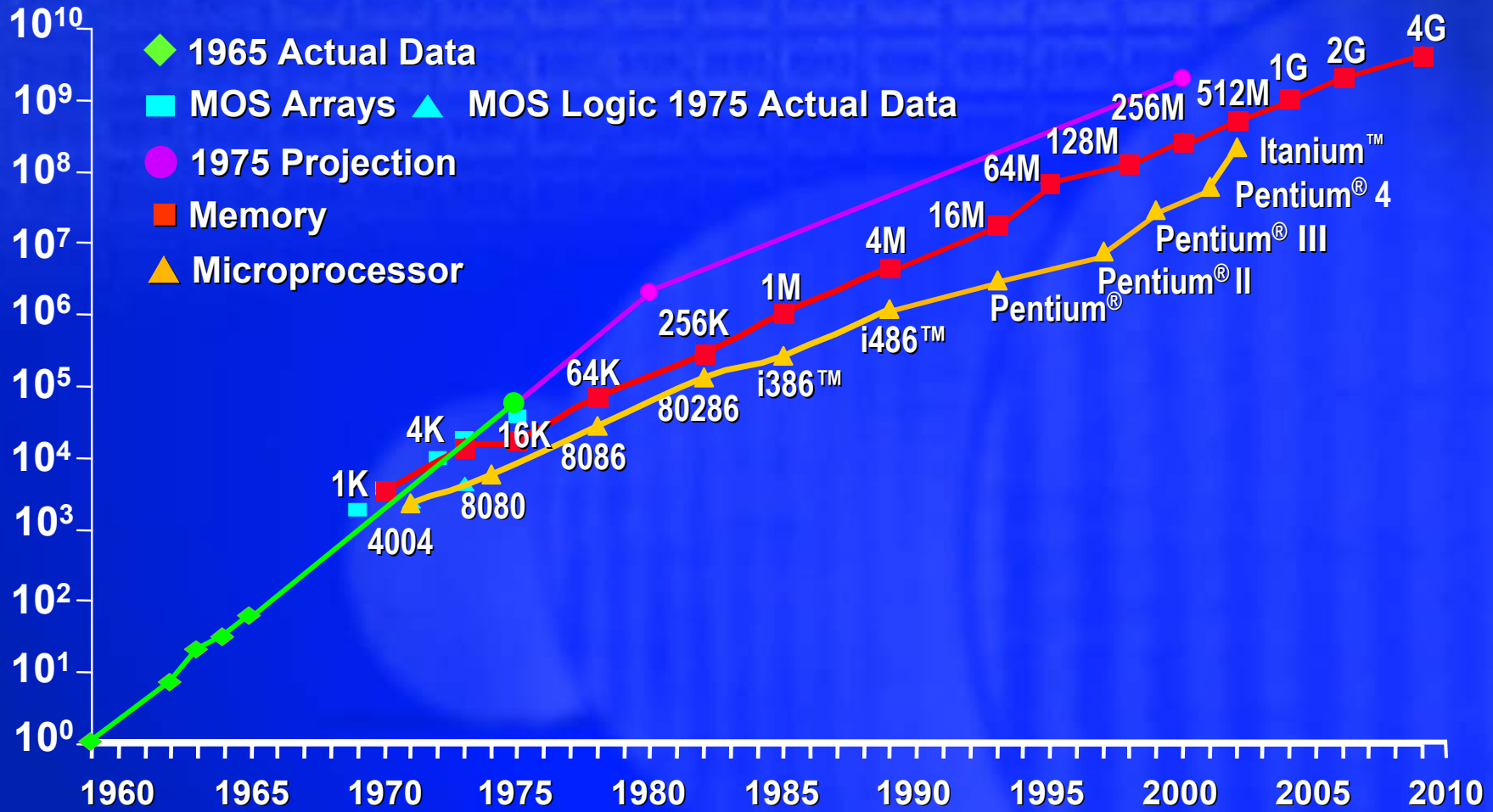
Electronics Magazine (35<sup>th</sup> anniversary), April 19, 1965



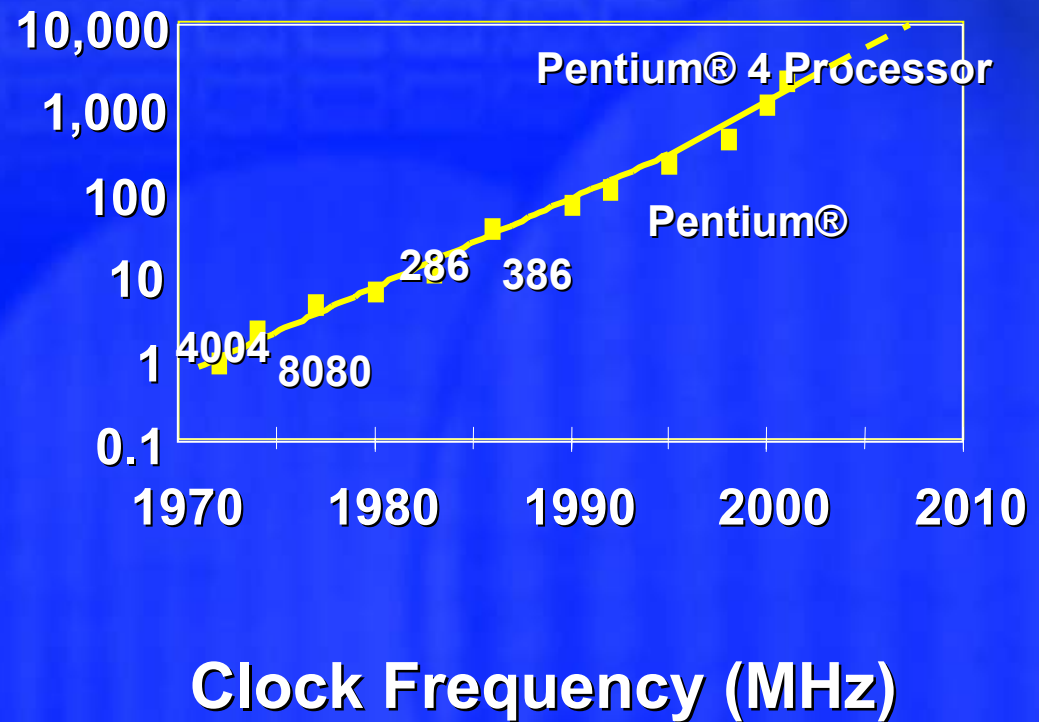
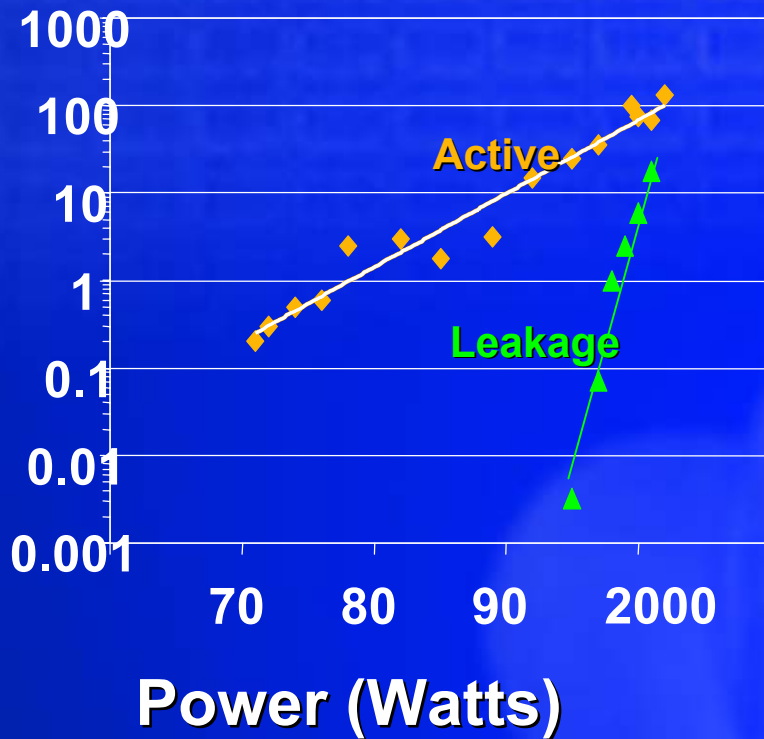
# Moore's Law continues to be the benchmark

Transistors

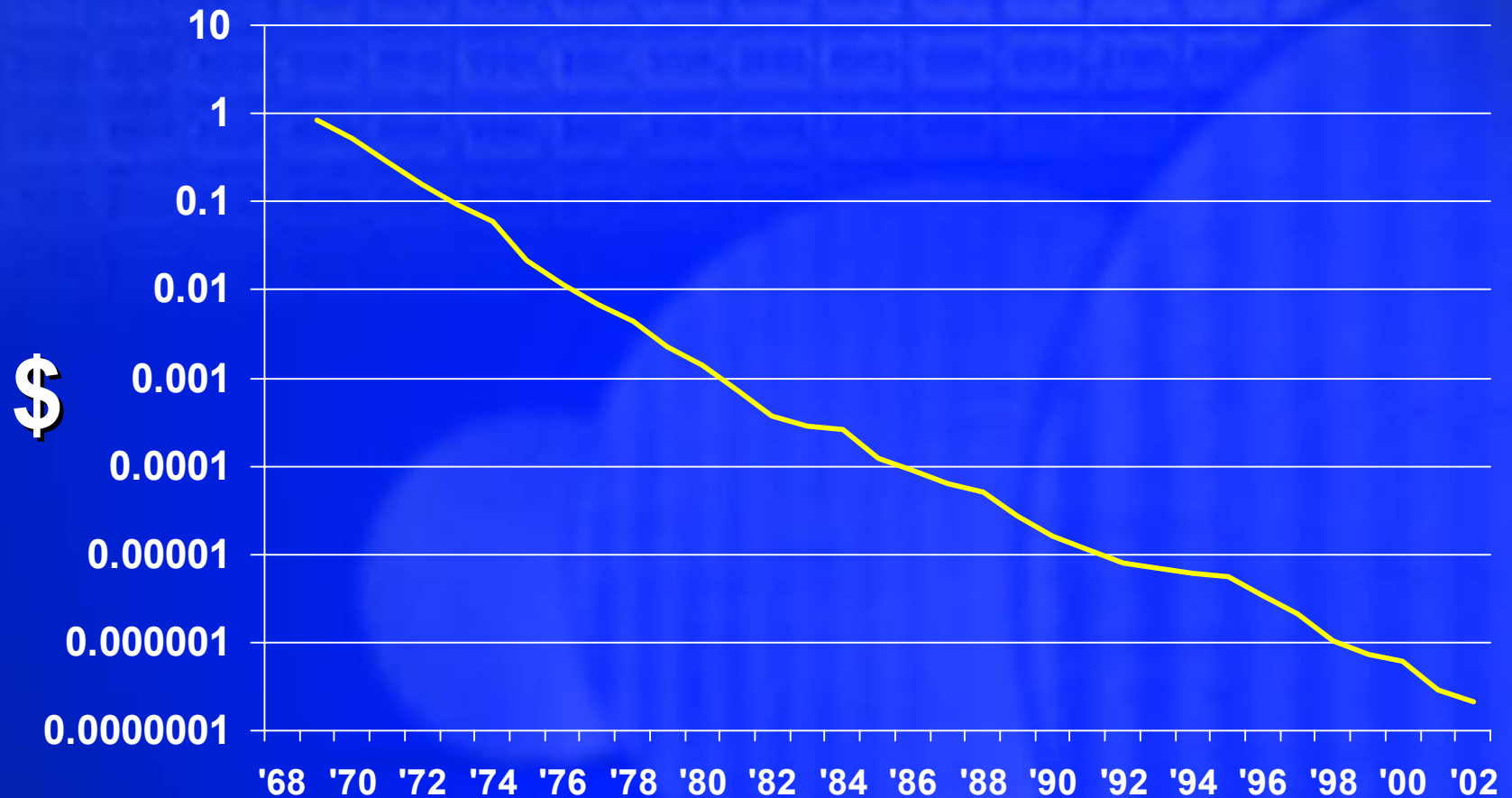
Per Die



# Effects of Scaling



# Effects of Scaling: Cost



# The beauty of silicon

For four decades, the semiconductor industry has steadily reduced the unit cost of IC components by

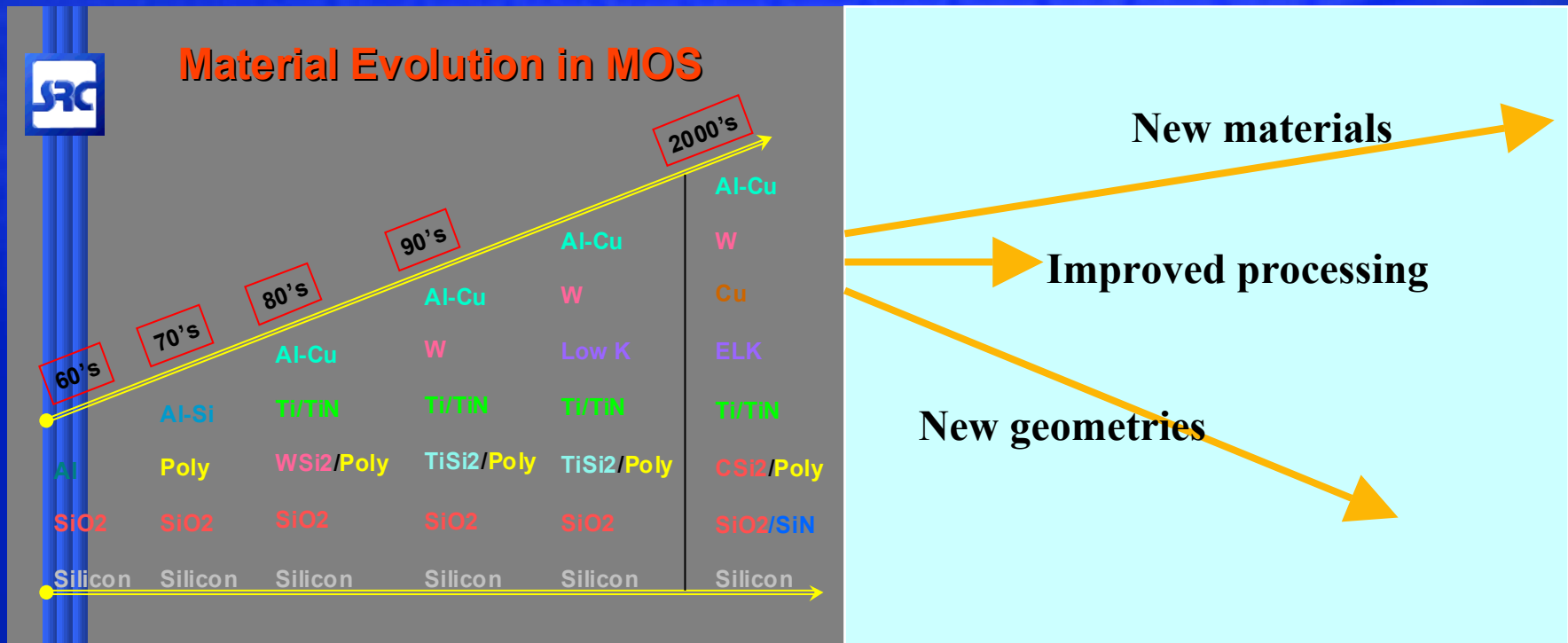
SCALING

1. Scaling device dimensions downward

2. Scaling wafer diameter upward

	1990	1995	2000
DRAMs	4 MB	64 MB	1 GB
Feature size	0.8 $\mu\text{m}$	0.35 $\mu\text{m}$	0.15 $\mu\text{m}$
Wafer diameter	6"	8"	12"
Cost per Megabit	\$6.50	\$3.14	\$0.10

# The ingredients of scaling



Scaling Will continue as long as

$(\delta \text{ cost}) / (\delta \text{ performance}) < \text{alternate technologies}$



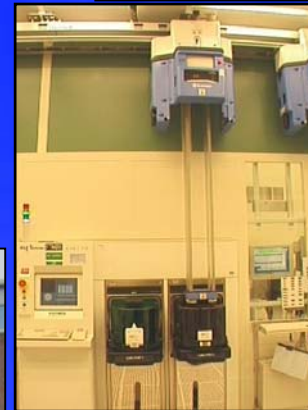
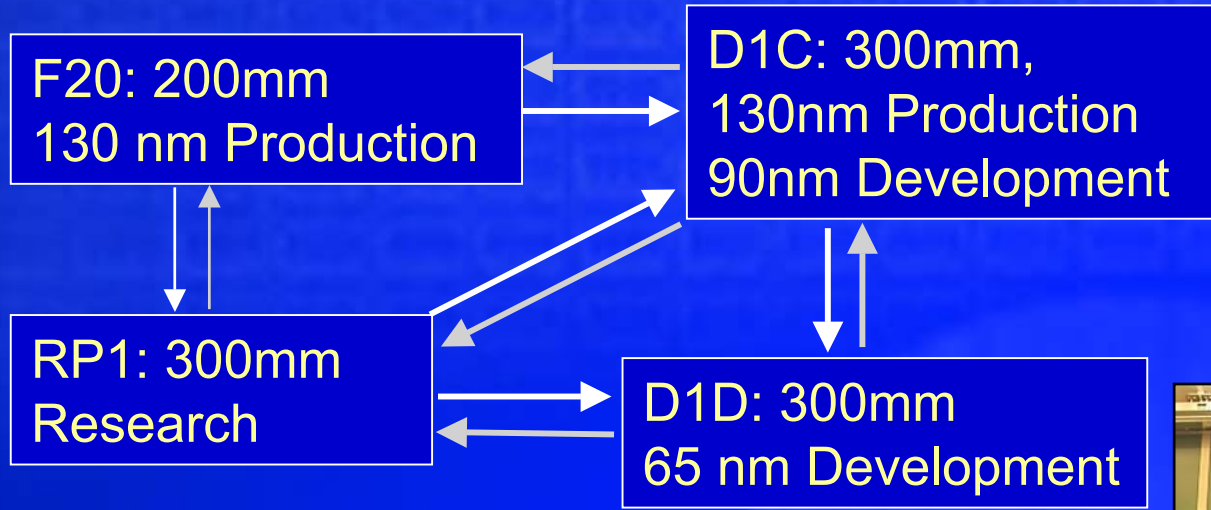
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# Silicon Research at Intel

- **Logic Technology Development ( OR, CA, AZ)**
  - Lithography, Transistors, Interconnects, Packaging, Environmentally Benign Materials
- **Non-Volatile Memory**
  - Ovonics (CA)
  - Polymers (OR)
- **Opto-electronics (CA)**
- **MEMS ( CA)**
- **Biotechnology ( CA)**

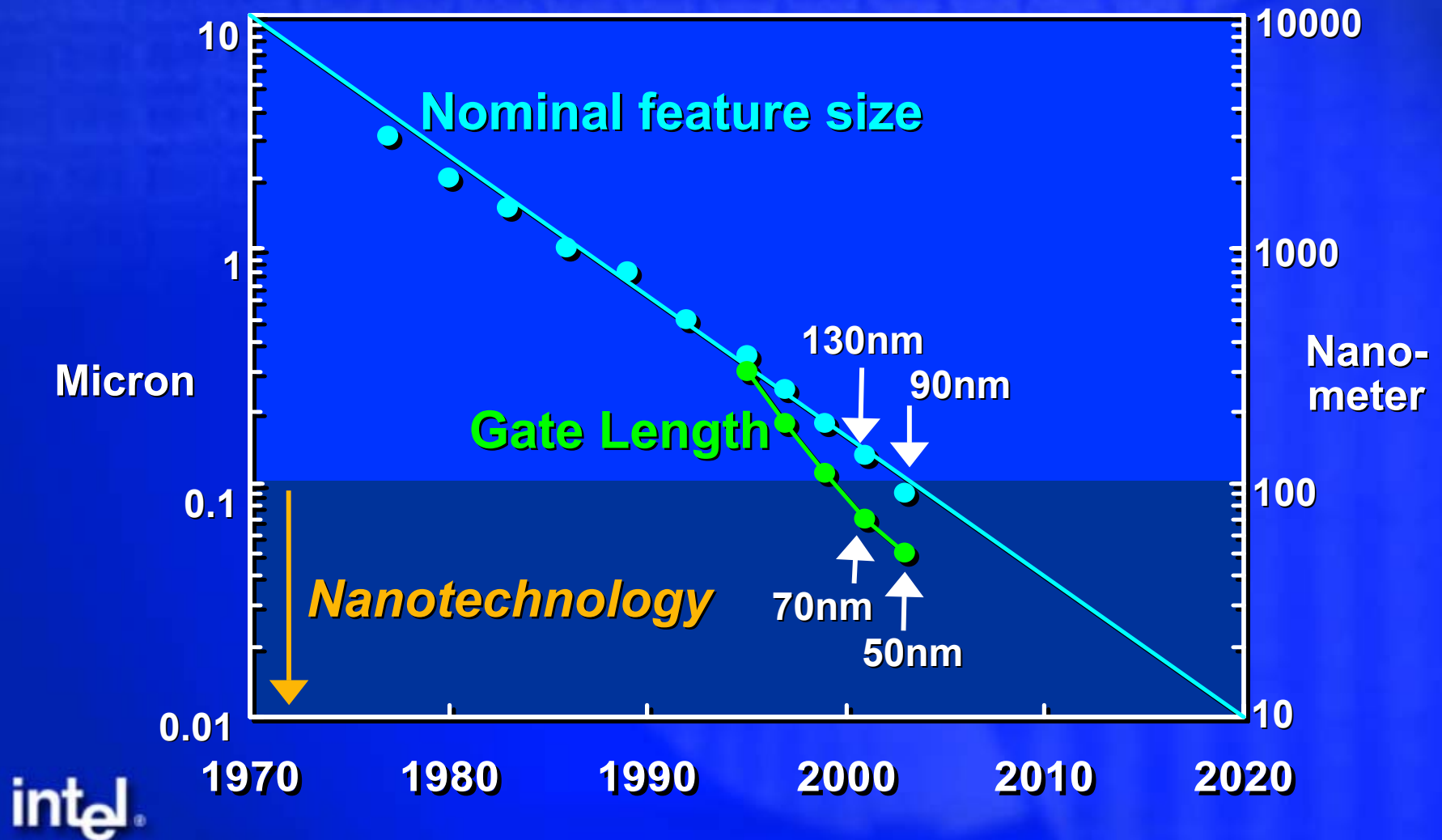
# Production, Development and Research Synergy



Ronler Acres



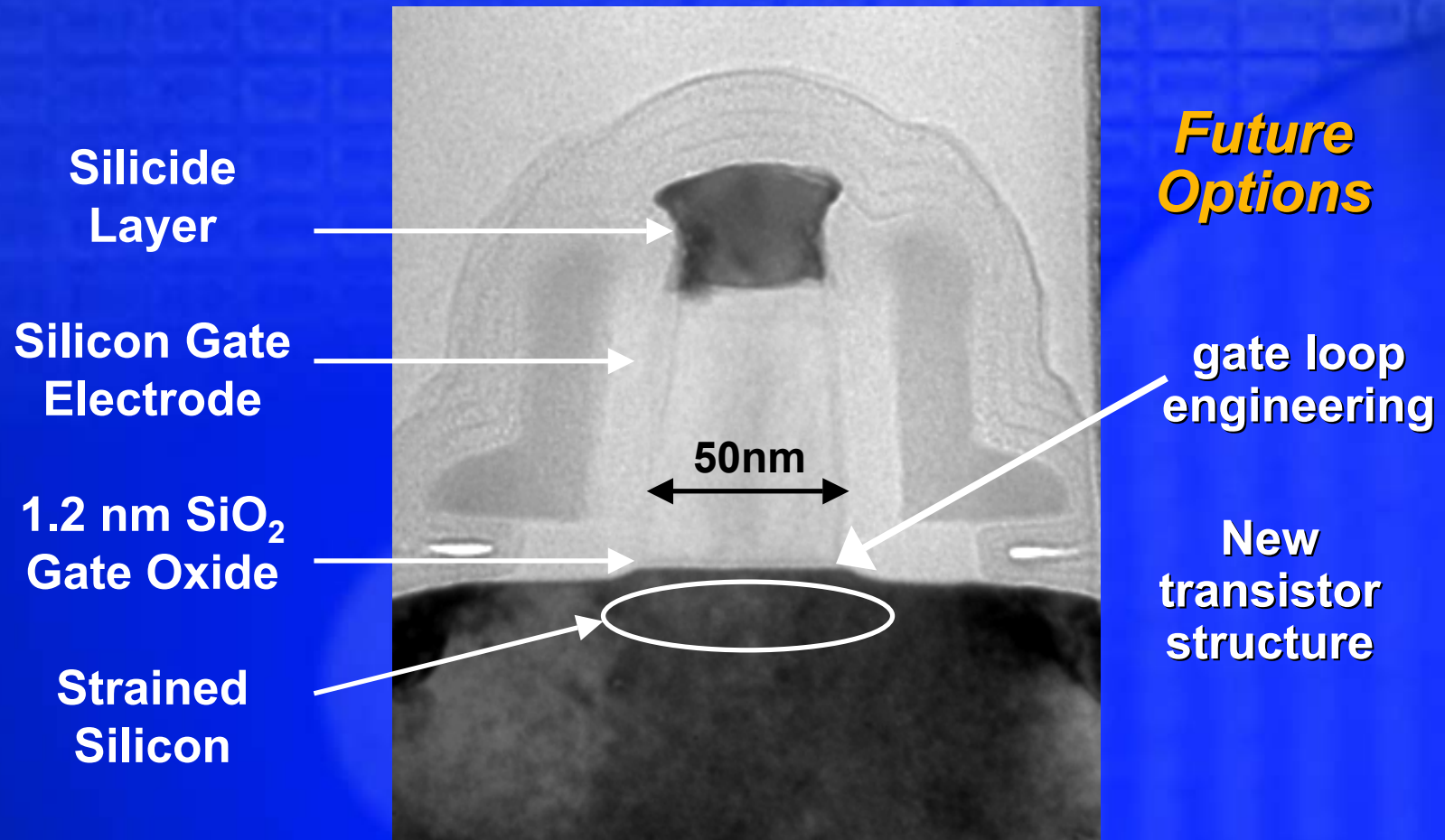
# Intel in Production with Nanotechnology (< 100nm)





# 90nm Logic Technology

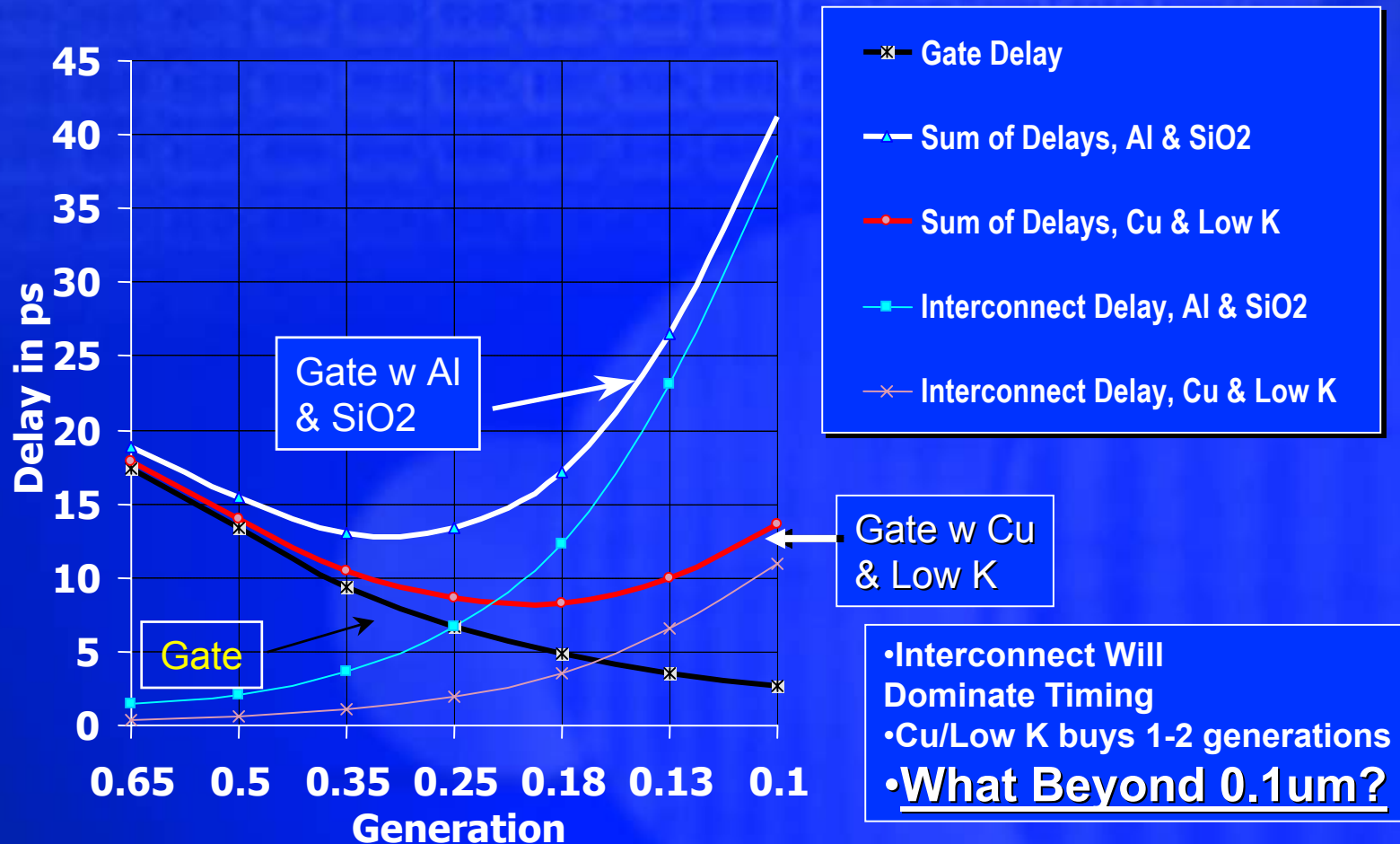
# 90 nm Generation Transistor



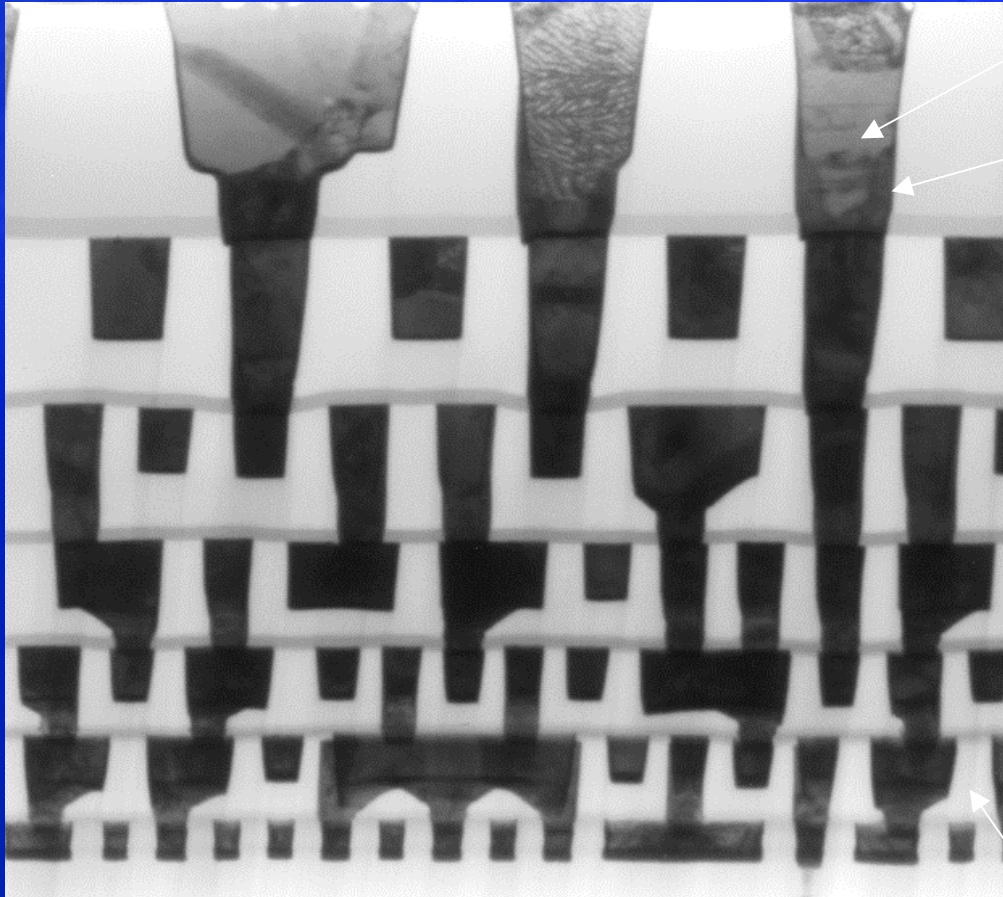
Source: Intel

50 nm  $L_{\text{GATE}}$  + 1.2 nm Oxide + Strained Silicon  
for industry leading transistor performance

# Interconnect Challenges: Delay

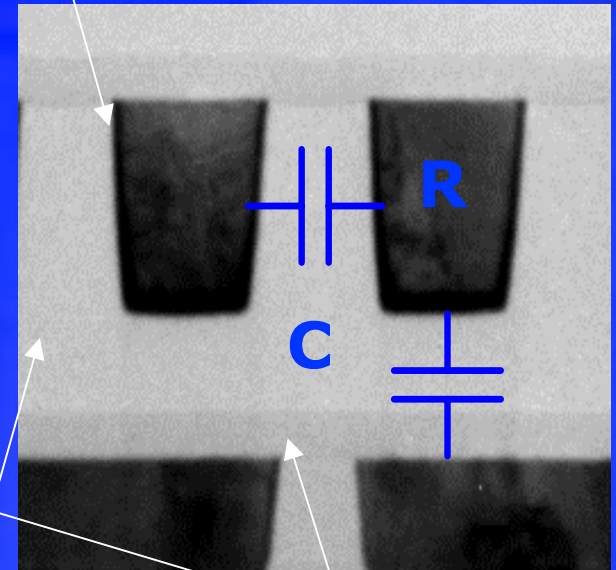


# 90nm Interconnects



● copper interconnects

● thin barriers



● etch stop

● low K dielectrics



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# How do we continue to drive Moore's Law?

- CMOS scaling will continue for  $> 10$  years
  - Si CMOS + New Materials
  - Dielectrics and Gate
  - Interconnect
  - Channel
- Nanoscience research is needed to facilitate radical new scalable technologies in the future
  - Need to identify most promising options (materials, processes, structures)
  - Must utilize silicon technology's foundation

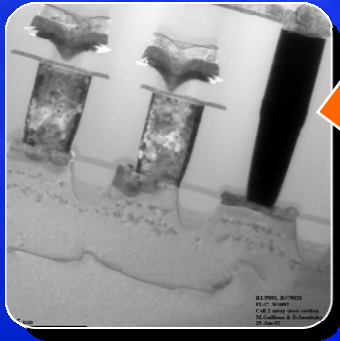
# Technical criteria

- *CMOS compatibility*
- *Energy efficiency*
- *Scalability*
- *Performance*
- *Architectural compatibility*
- *Sensitivity to parametric variation*
- *Room temperature operation*
- *Stability and reliability*

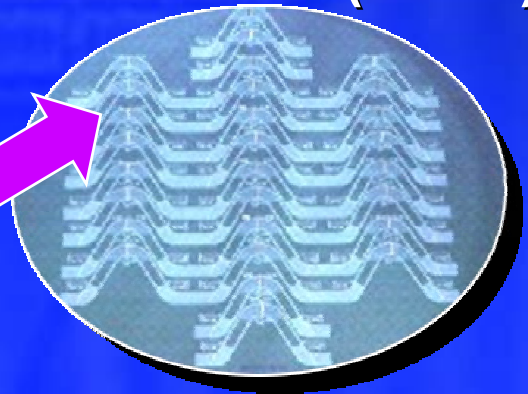
***“No exponential lasts forever  
but we can delay forever”***

# Adaptable and Versatile Silicon Technology

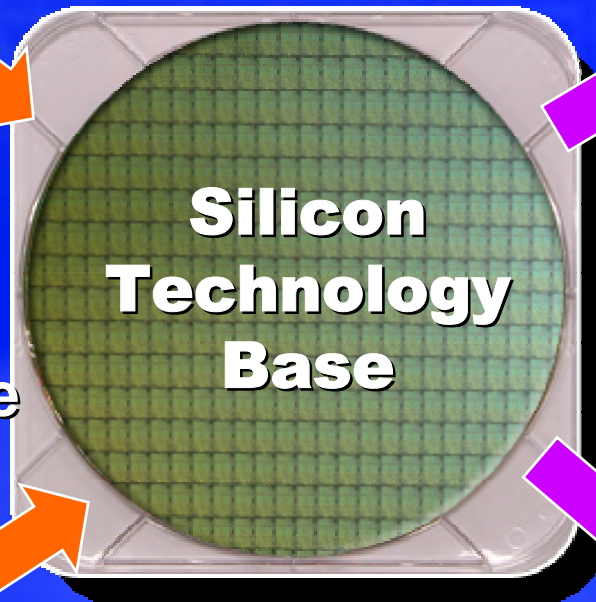
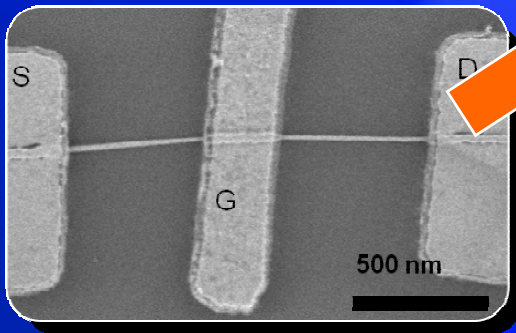
Ovonic Memory



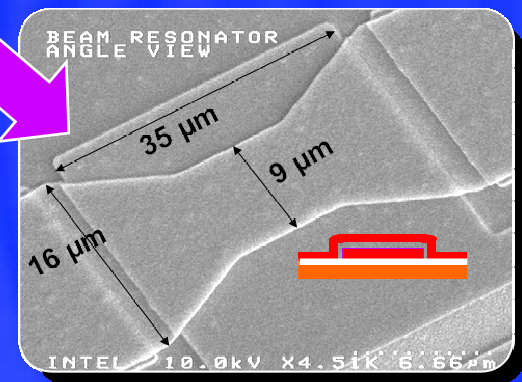
Photonics (AWG)



Nanotube/Nanowire Transistors



MEMS for RF



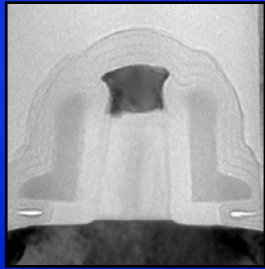


# Key Challenges to Scaling

- Transistor
  - Gate Oxide Leakage
  - Source-drain leakage
  - Short Channel Performance
  - Vcc scaling
- Patterning
- Interconnects, Packaging
  - RC delay
  - Power delivery, distribution
  - Thermal Management

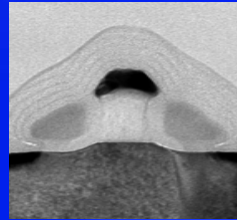
# Intel Nano Transistors

90nm Node  
2003



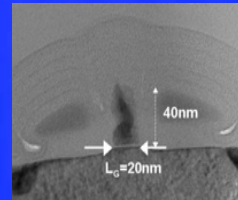
50nm Length  
(IEDM2002)

65nm Node  
2005



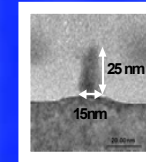
30nm Prototype<sup>1</sup>

45nm Node  
2007



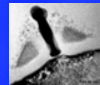
20nm Prototype<sup>2</sup>

32nm Node  
2009



15nm Prototype<sup>3</sup>

22nm Node  
2011

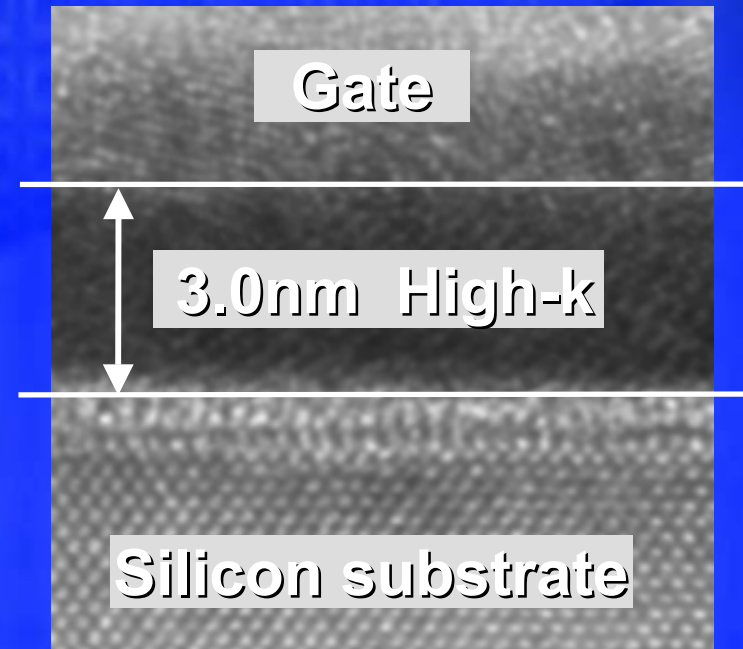
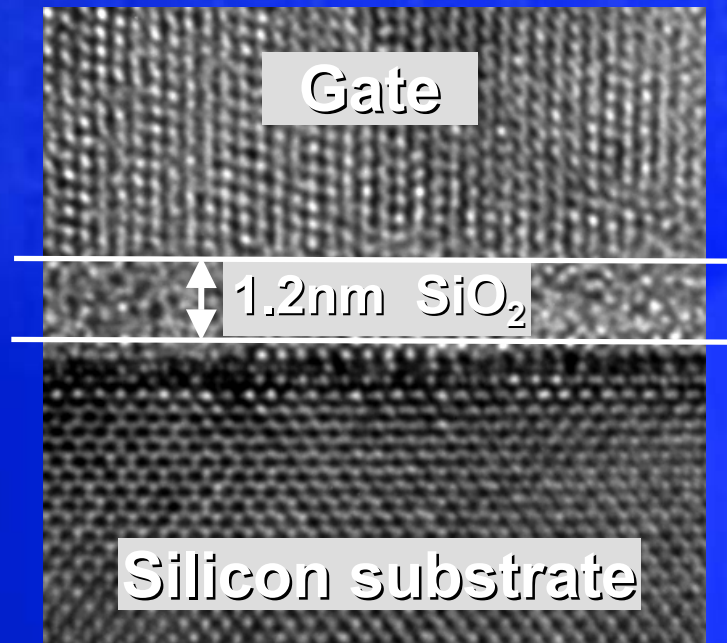


10nm Prototype<sup>4</sup>

## References

1. IEDM, R. Chau et al., 12/00
2. 2001 Silicon Nanoelectronics Workshop, R. Chau et al., 6/01
3. TeraHertz Transistor press briefing, G. Marcyk & R. Chau, 11/01
4. 61st Device Research Conference, R. Chau et al., 6/03

# Nanotechnology for Gate Dielectrics



Source: Intel

## 90nm process

## Experimental high-k

Capacitance

1X

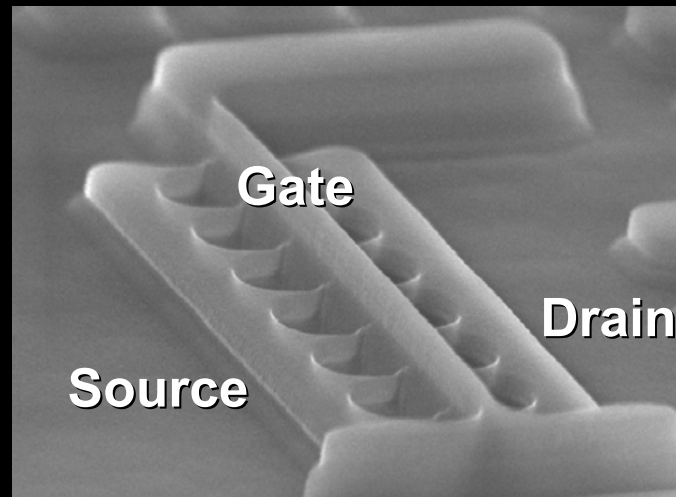
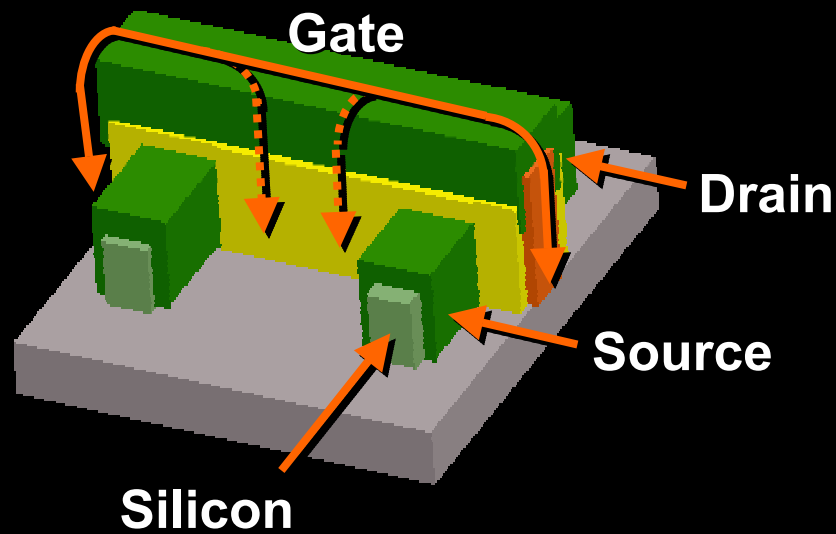
1.6X

Leakage

1X

< 0.01X

# Experimental Tri-Gate Transistor



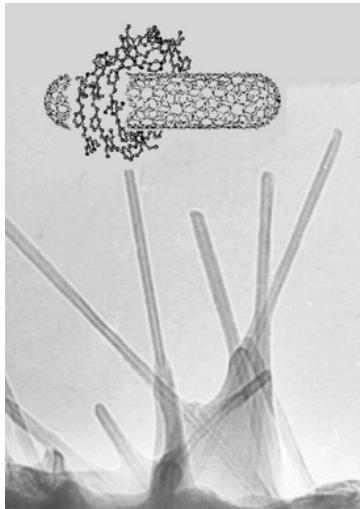
Source: Intel

- Improved version of TeraHertz transistor
  - Better performance
  - Scalable to smaller sizes (low leakage)
  - Possible intercept towards end of decade?

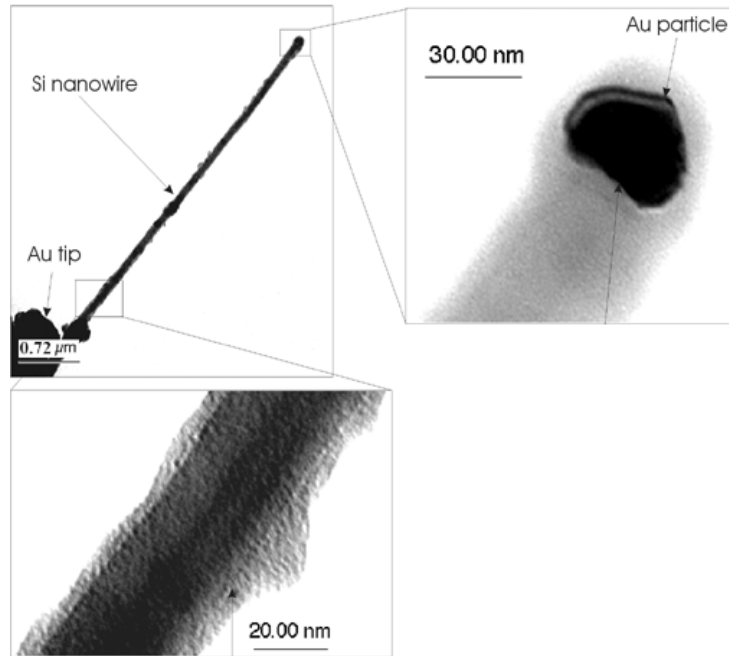


# Future Nanotechnology will compliment & extend Silicon Technology

## Silicon Nanowire\*



## Carbon Nanotube\*\*

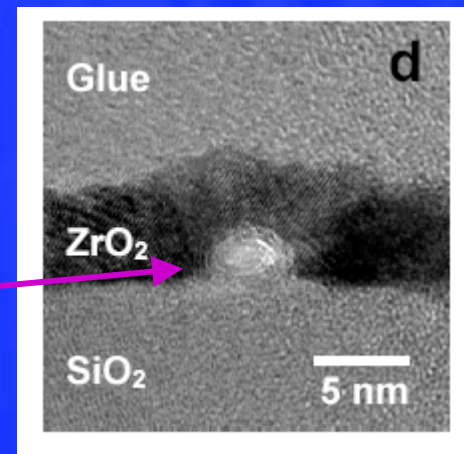
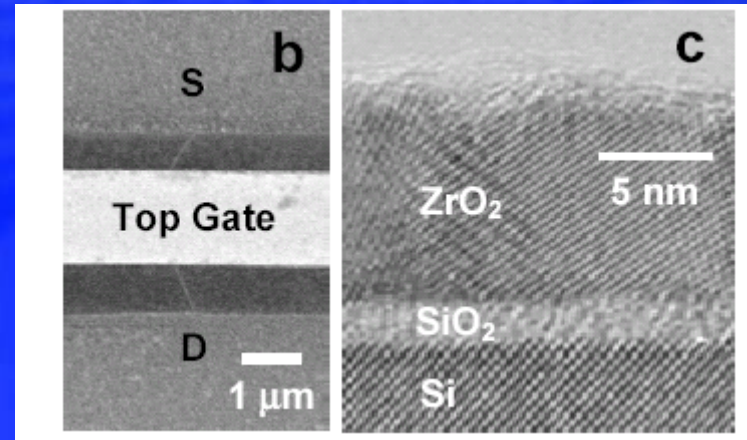
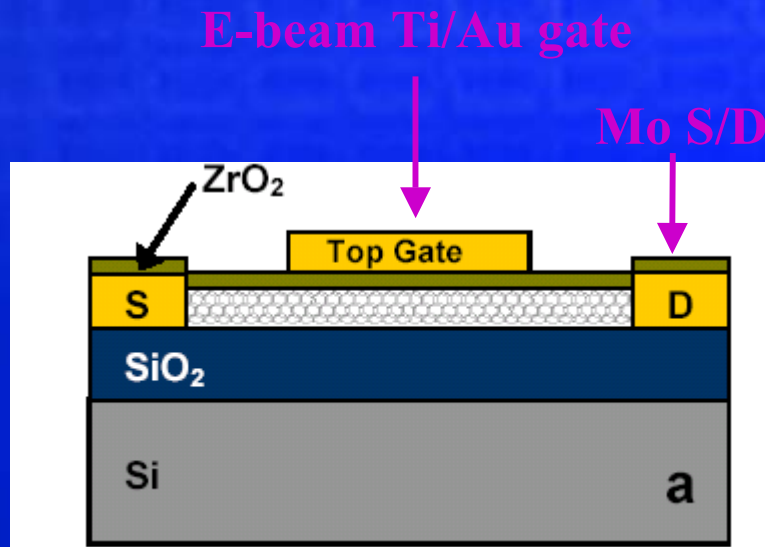


## Nanotube/Nanowire Transistors

\*Source: Holmes et al, University College Cork

\*\*Source: Blau et al, Trinity College Dublin

# CNT-FET Device Structure

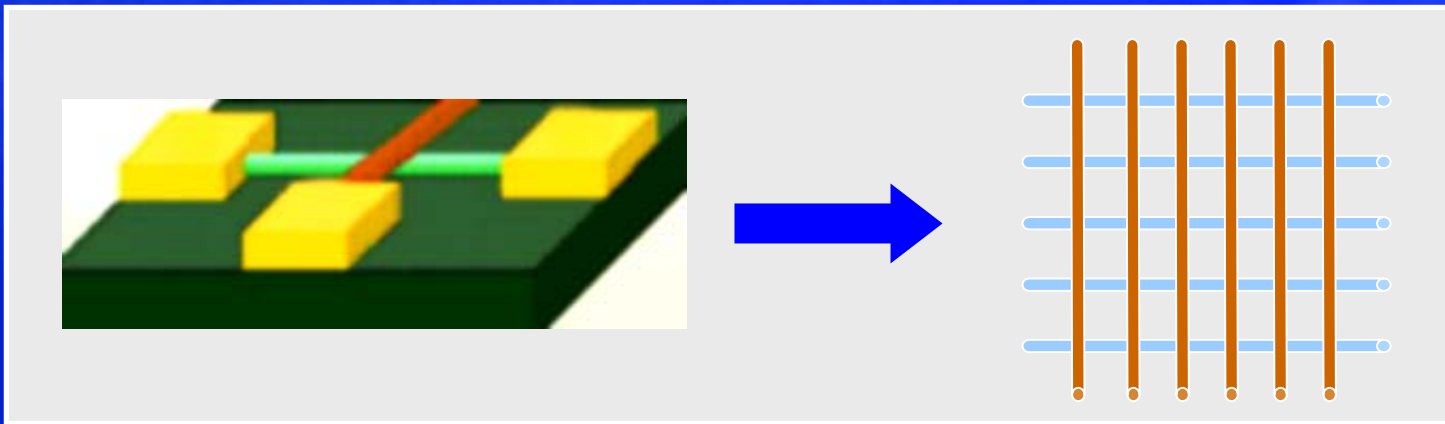


1.4 nm diameter single wall CNT

McEuen et. al, . Cornell University

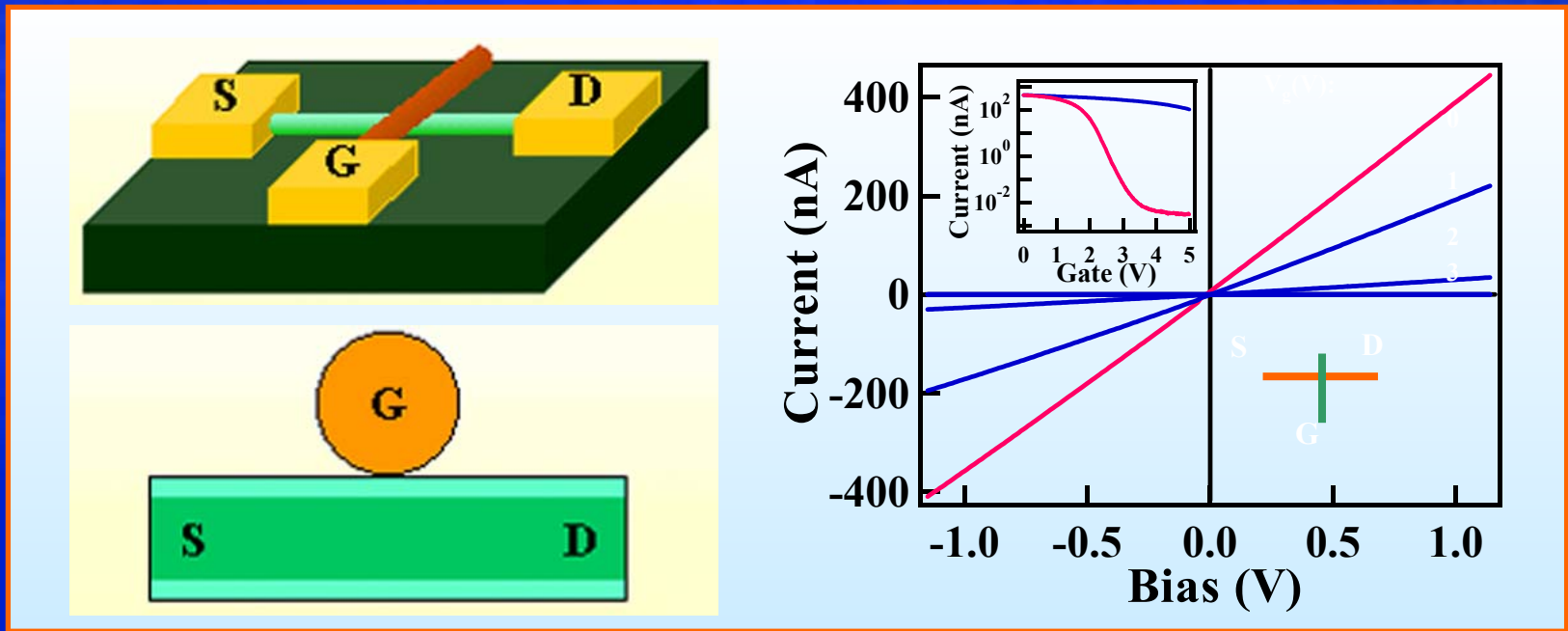


# Crossed Nanowire Structures: A Powerful Strategy for Creation & Integration of Nanodevices



- Nanowires serve dual purpose: both active devices and interconnects.
- All key nanoscale metrics are defined during synthesis and subsequent assembly.
- Crossed nanowire architecture provides natural scaling and potential for integration at highest densities.
- No additional complexity (with added material).

# Crossed Nanowire FETs

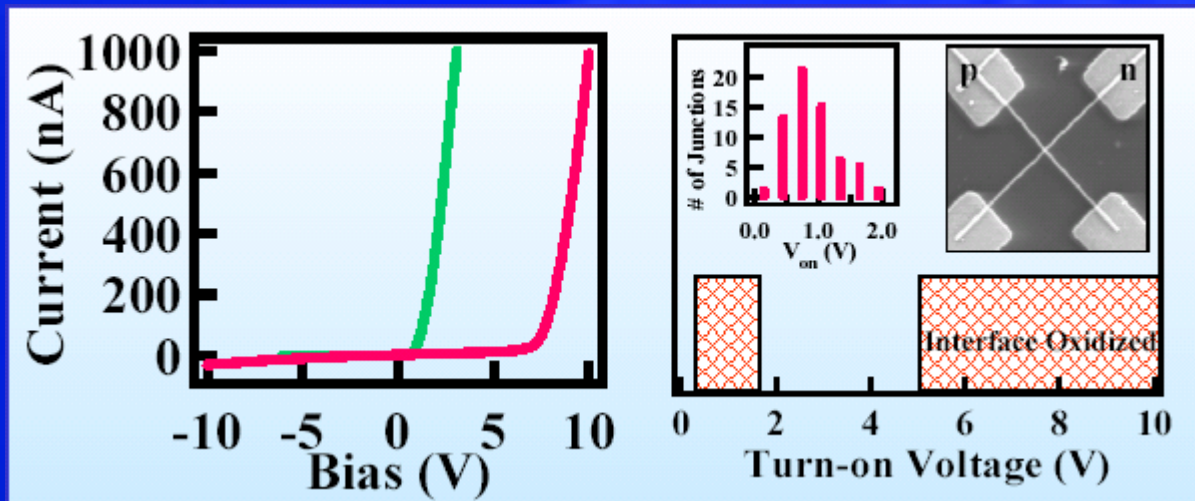


- In crossed nanowire FETs (cNW-FET), all critical nanoscale metrics are defined by synthesis and assembly:
  - channel width by the active nanowire diameter (to 2 nm)
  - channel length by the gate nanowire diameter (to 1-2 nm)
  - gate dielectric oxide coating on the nanowires (to 1 atomic layer)
- The conductance of cNW-FETs can be changed by more than  $10^5$ -times with less than 0.1 V variation in the nano-gate.



# Device Demonstrated

## P-N Junction

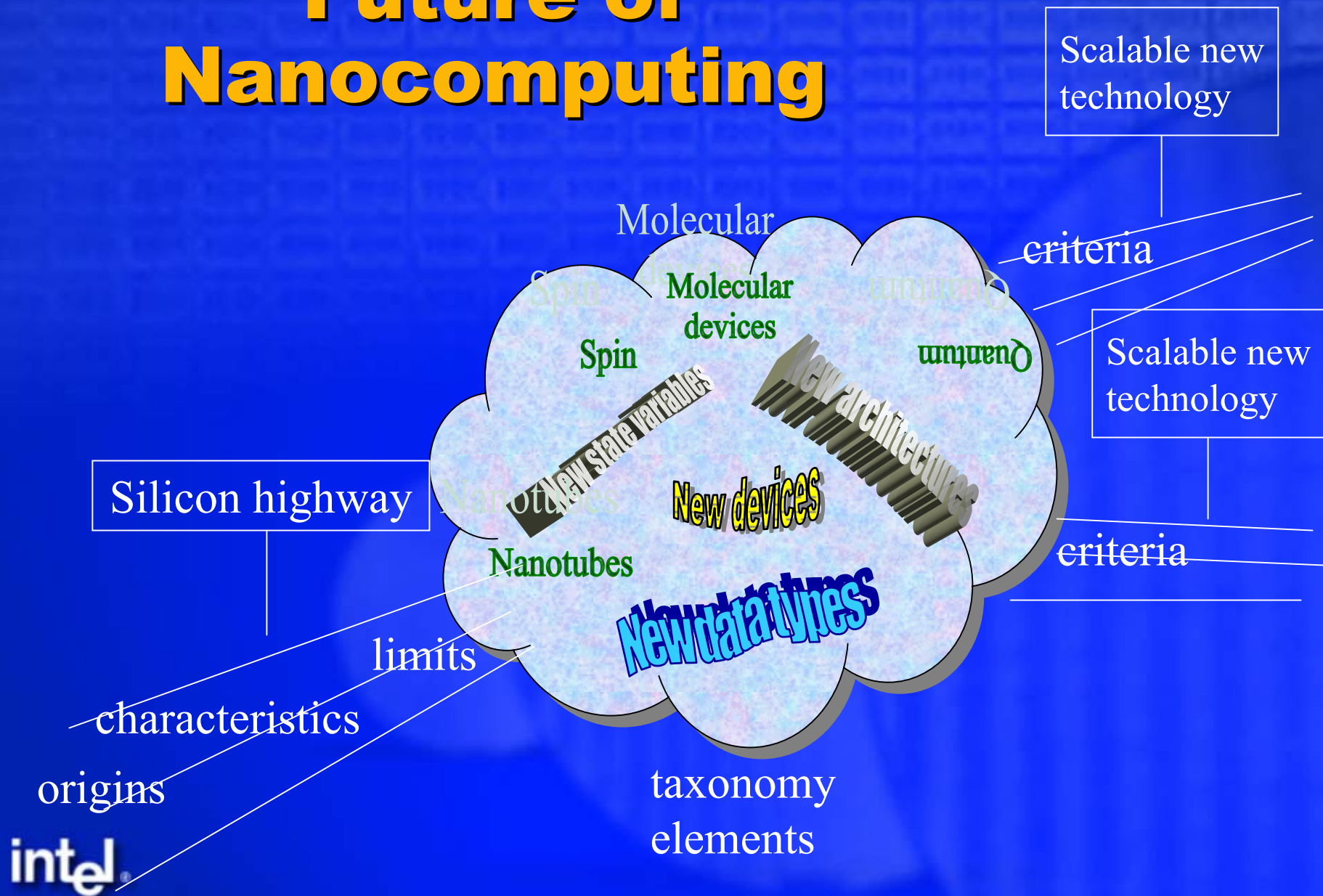


Lieber/Harvard

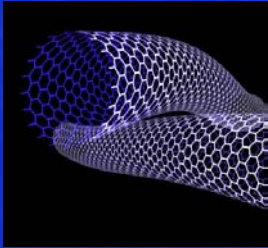
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# Future of Nanocomputing



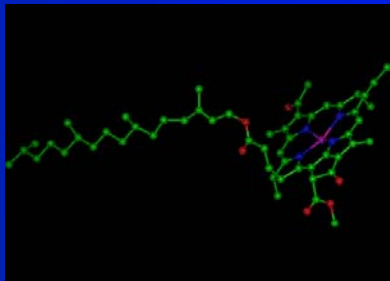
# Nanotech Building Blocks



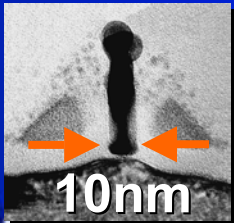
Sub 100nm particles



Molecular Assembly (directed and self assembly)



Macromolecules

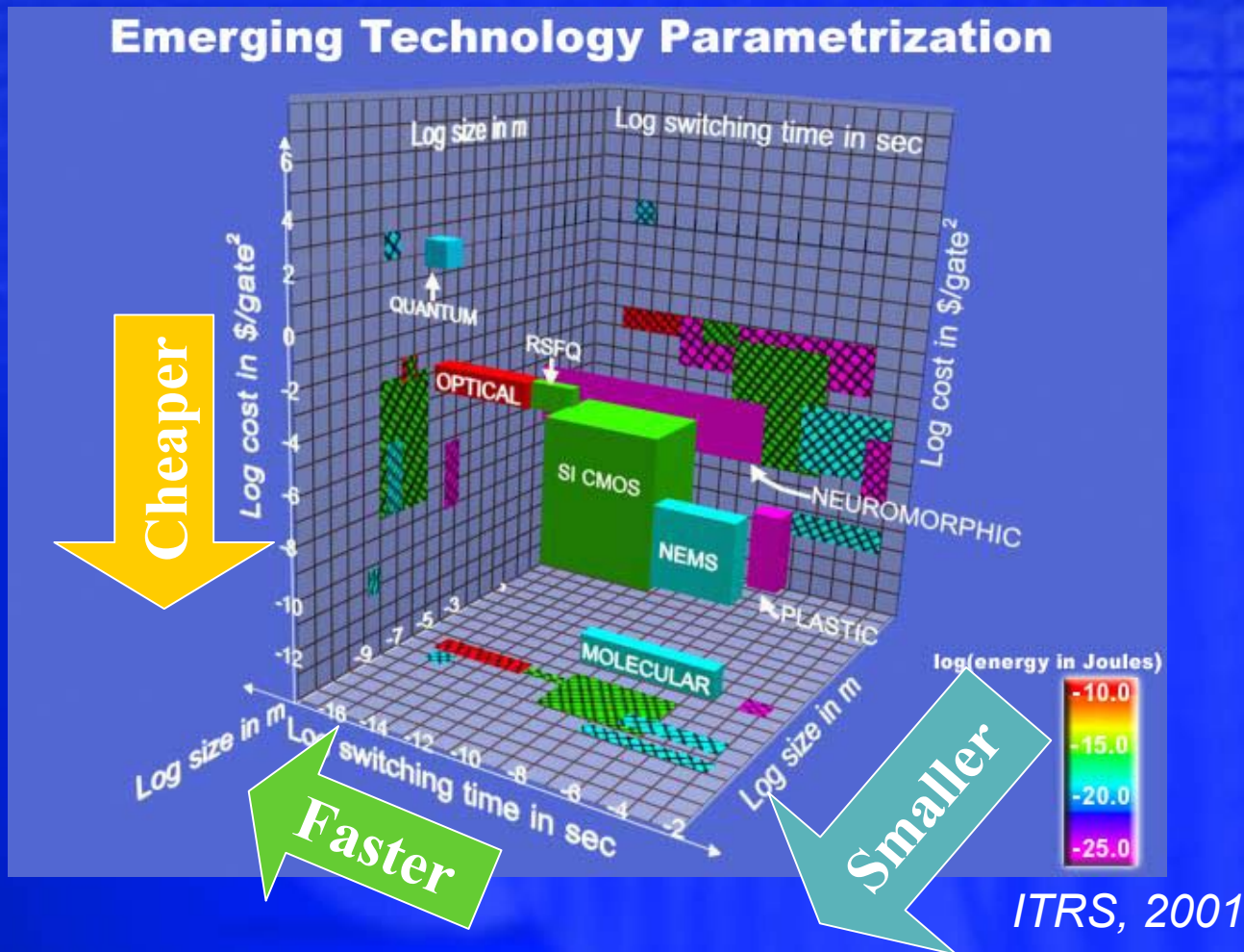


Sub 100nm structures

intel



# Some alternative logic devices



**Alternative logic devices exist which are  
intel. complimentary to scaled silicon**

# Conclusions

- Intel's sub-100nm technology is already a production reality and continues to follow Moore's Law
- We believe the Silicon nanotechnology is extendable for at least 10 years
- Nanoscience research is needed to facilitate radical new scalable technologies for the future – we are open-minded about future options and collaborations between industries, universities and governments is essential

For further information on Intel's silicon technology,  
please visit the Silicon Showcase at  
[www.intel.com/research/silicon](http://www.intel.com/research/silicon)